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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

31046 U.S. PTO
10/059294
01/31/02

In re Application of: :
Hisaaki OGURI et al.) Prior Examiner: K. Brown
Application No.: Continuation of Appln. :
No. 09/388,372, filed) Prior Group Art Unit: 2851
September 1, 1999 :
Filed: January 31, 2002 :
For: POSITION DETECTION : January 31, 2002
APPARATUS HAVING A)
PLURALITY OF DETECTION :
SECTIONS, AND EXPOSURE)
APPARATUS :

The Commissioner for Patents
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

To comply with the duty of disclosure under 37 CFR 1.56 and in accordance with the practice under 37 CFR 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed PTO-1449 Form. Copies of the listed documents are also enclosed.

(1) Japanese patent document No. 7-302748 relates to a semiconductor manufacturing apparatus having a plurality of measurement devices and a semiconductor manufacturing method using the same. This document corresponds to U.S. Patent No. 5,658,700, a copy of which is also enclosed.

(2) Japanese patent document No. 10-289871 relates to a projection exposure device.

(3) Japanese patent document No. 10-284393 relates to an aligner and fabrication of a device.

(4) Japanese patent document No. 10-64980 relates to a device and a method for detecting surface position.

(5) Japanese patent document No. 9-246356 relates to a surface position setting method.

(6) Japanese patent document No. 9-236425 relates to a surface position detector.

(7) Japanese patent document No. 9-45608 relates to a surface position detection method.

(8) Japanese patent document No. 7-201698 relates to a pattern exposing sensitive layer forming method and a semiconductor circuit using it.

(9) Japanese patent document No. 3-253917 relates to a method and device for setting an interval of first and second objects.

(10) Japanese patent document No. 57-204547 relates to an exposing method.

(11) Japanese patent document No. 11-176735 relates to a surface position detection method and aligner using the same.

(12) Japanese patent document No. 11-121320 relates to a method and device for detecting surface position.

(13) Japanese patent document No. 11-111610 relates to an aligning method and equipment thereof.


(14) Japanese patent document No. 11-191522 relates to a method and apparatus for exposure.

Applicants request that the Examiner consider the cited information and return an initialed copy of the enclosed PTO-1449 Form indicating that such information has been considered.

Applicants believe that no fees should be incurred in connection with filing this paper. Nevertheless, the Commissioner is authorized to charge Deposit Account No. 06-1205 should any fees be associated herewith. A duplicate of this paper is enclosed for this purpose.

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address listed below.

Respectfully submitted,



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